Supporting Information

Magnetic and Electrical Properties of LuFe₂O₄ Epitaxial Thin Films with Self-assembled Interface Structure

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1. Figure S1: Crystal structure of $LuFe_2O_4$ and out-of-plane XRD patterns of the thin films grown for varied deposition times.

2. Figure S2: AFM images of LuFe₂O₄ thin film.



Figure S1. (a) Schematic illustration of crystal structure for $LuFe_2O_4$ viewed as a hexagonal system. (b) θ -2 θ out-of-plane XRD patterns for the $LuFe_2O_4$ thin films grown under diverse duration times. The diffraction lines ascribable to *h*-LuFeO₃ and Lu₂Fe₃O₇ phases are observed after 30 min deposition. All the diffraction lines observed for the specimen after 60 min deposition are assigned to LuFe₂O₄ phase.

Root Mean Square (RSM, nm)	3.912	1.036
Region (μ m × μ m)	3×3	

Figure S2. AFM images of LuFe₂O₄ thin film.